

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Priority Application Serial No. 10/039,456
Priority Filing Date December 31, 2001
 Inventor Ying Huang et al.
 Assignee Micron Technology, Inc.
Priority Group Art Unit 2829
Priority Examiner S.B. Geyer
 Attorney's Docket No. MI22-2347
 TITLE: An Improved Method, Structure and Process Flow to Reduce Line-Line
 Capacitance with Low-K Material

Commissioner for Patents
 Alexandria, VA 22313-1450

Attention: Official Draftsman


SUBSTITUTE DRAWING REQUEST

Please enter the enclosed substitute drawings in the above-referenced application
 in place of drawings originally filed. The content of the drawings are identical to those now
 on file in this application.

Acknowledgment of receipt of the formal drawings and their acceptance into the file
 is requested.

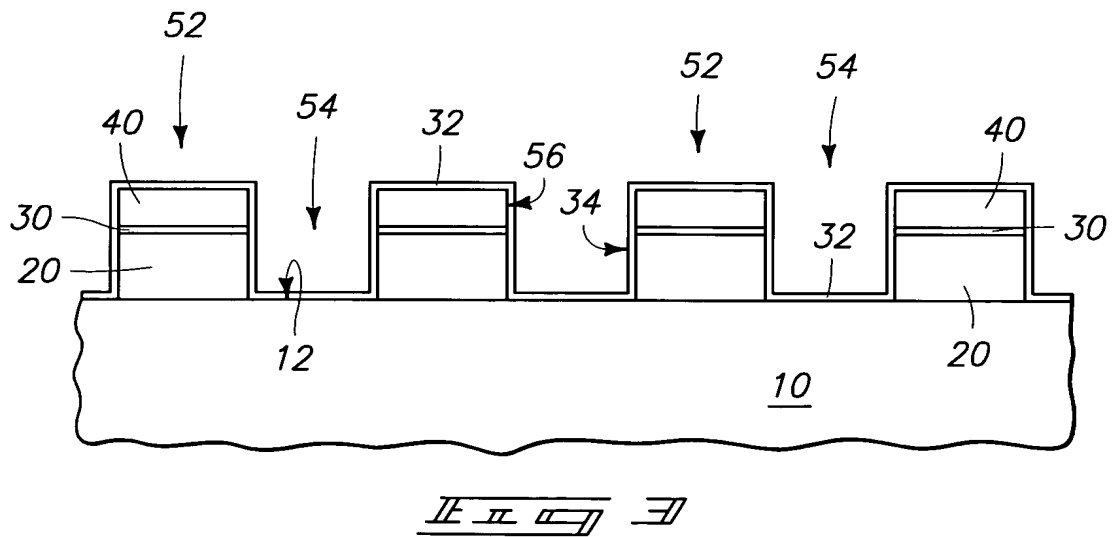
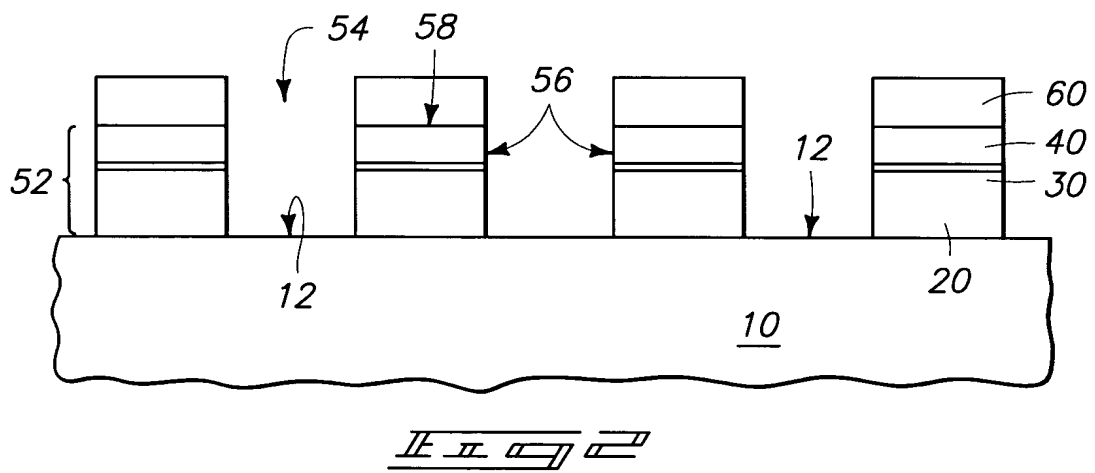
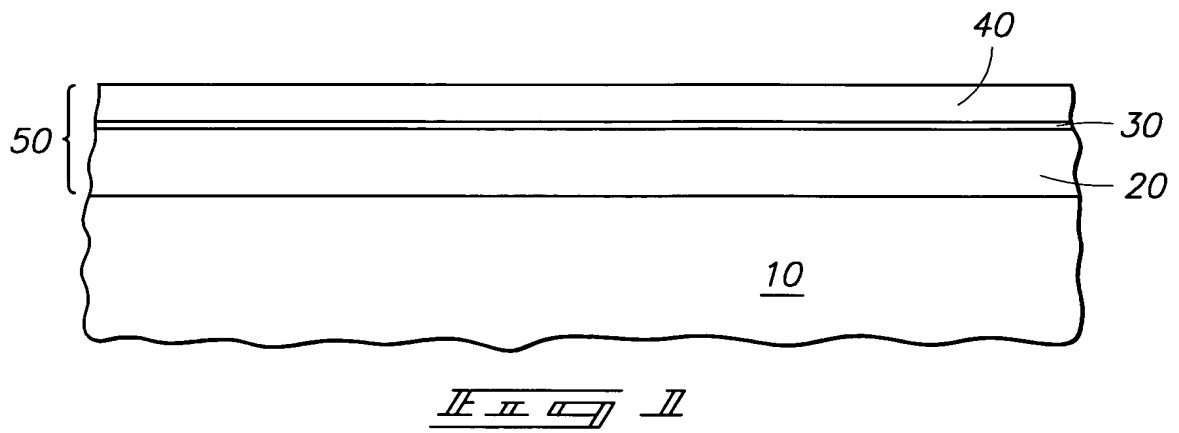
Respectfully submitted,

Date: 7-23-03

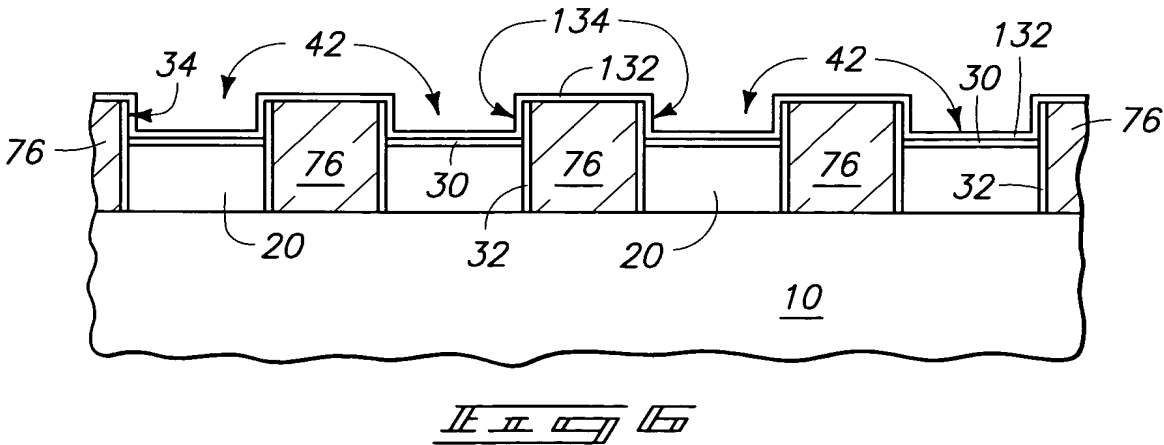
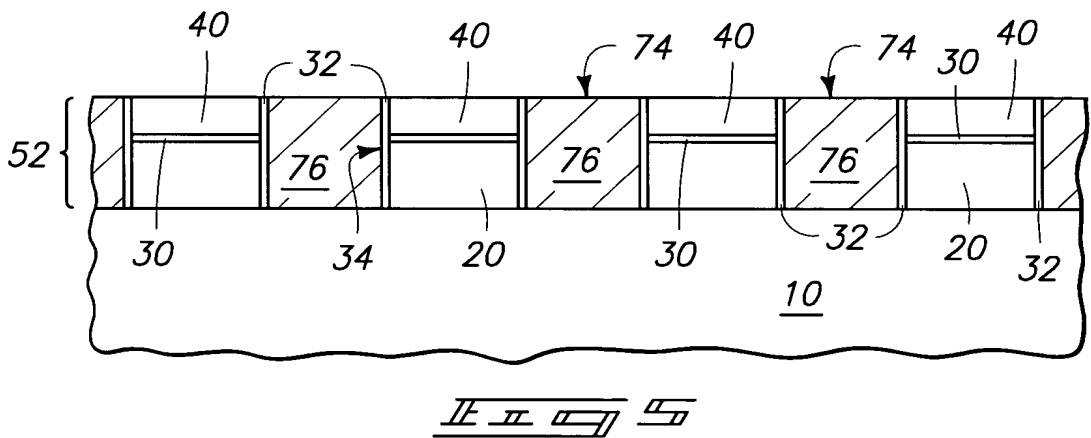
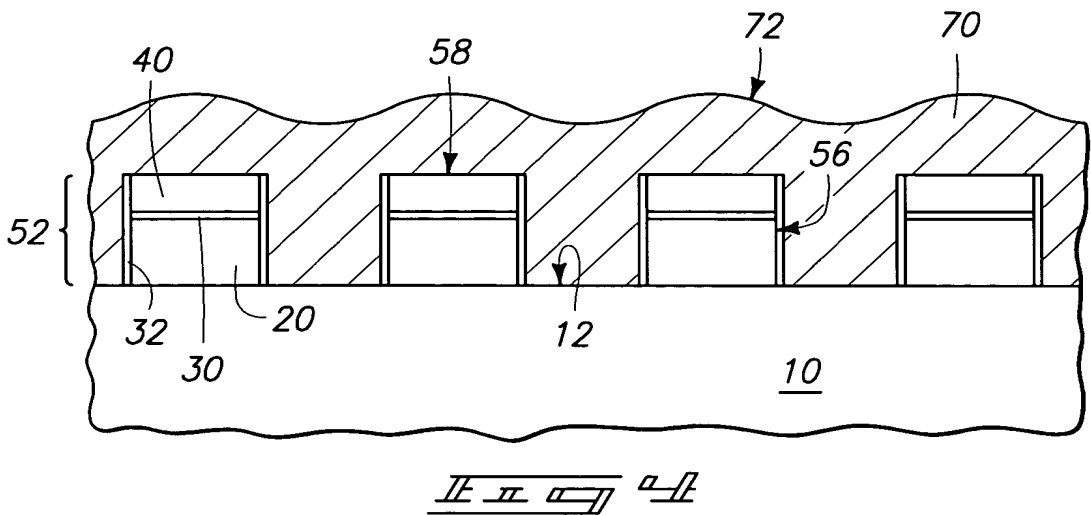
By: 
 D. Brent Kenady
 Reg. No.: 40,045
 WELLS ST. JOHN P.S.
 601 W. First Avenue, Suite 1300
 Spokane, WA 99201-3828
 (509) 624-4276

Enclosures: 5 Sheets of Formal Drawings, Figs. 1-14.

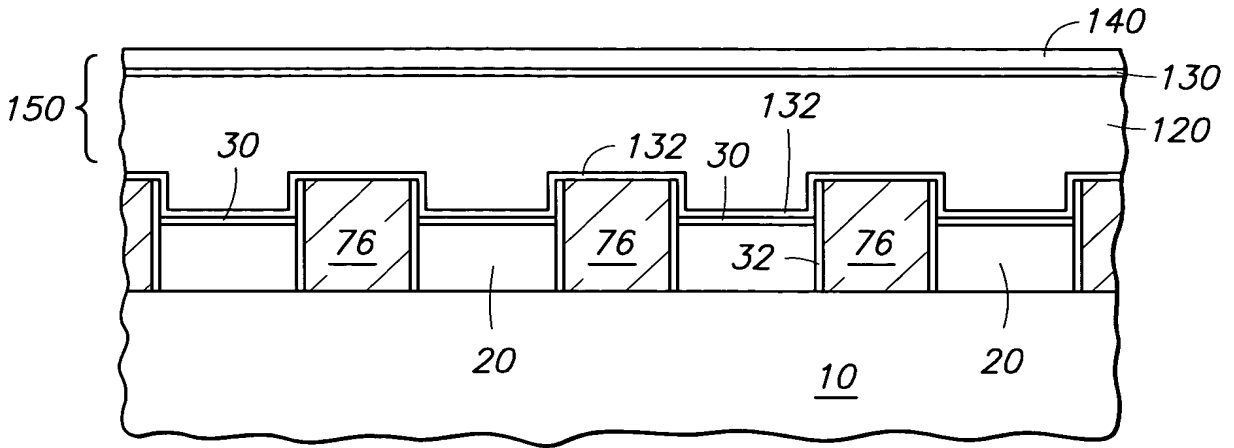
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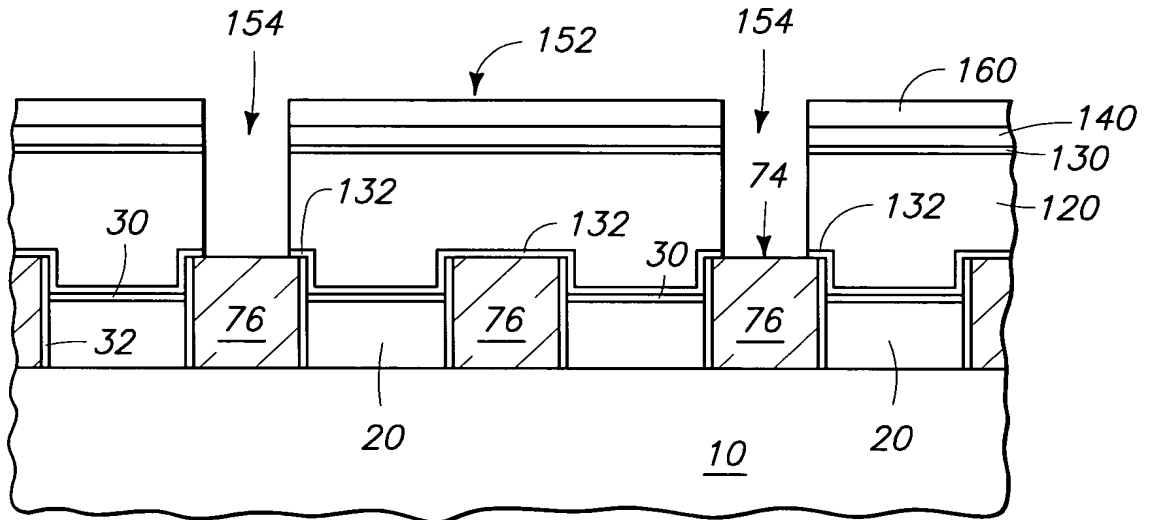
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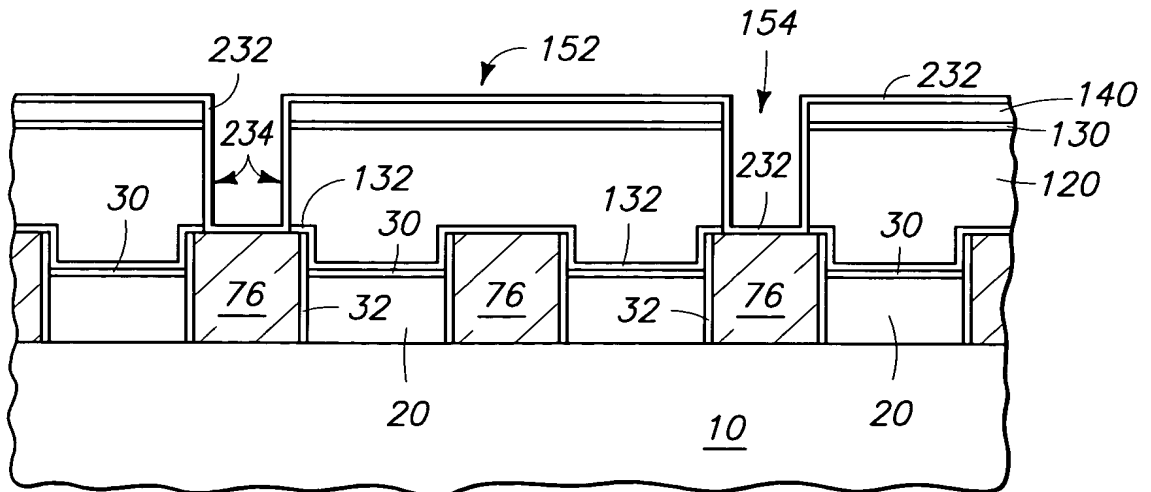
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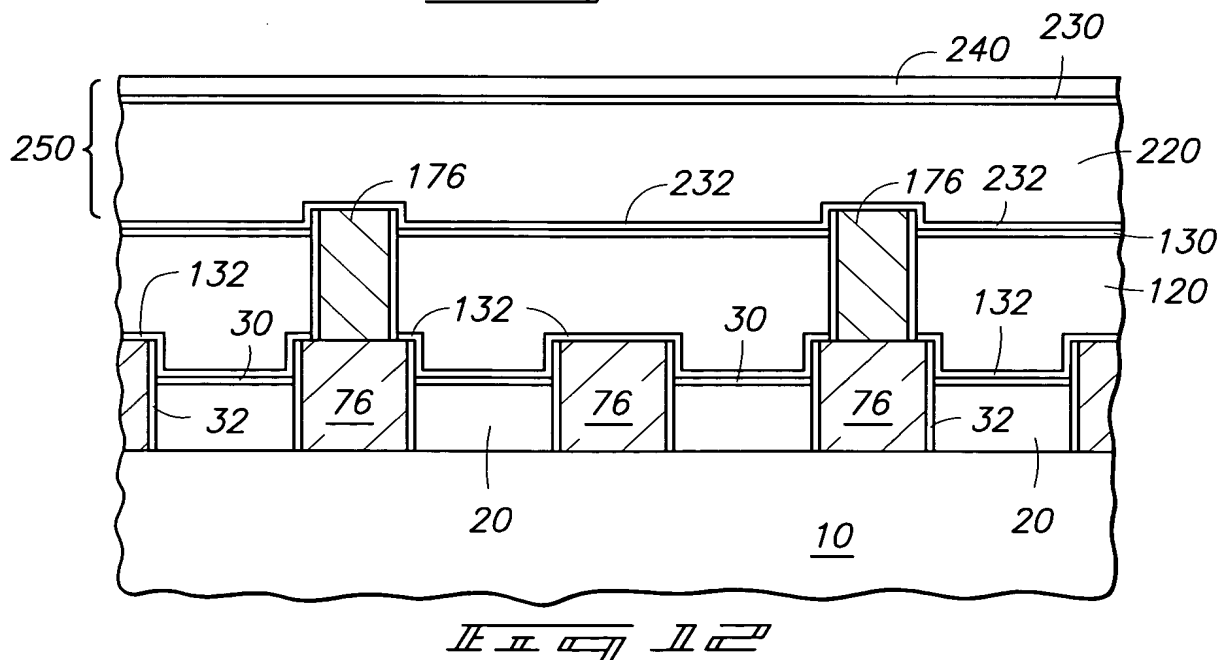
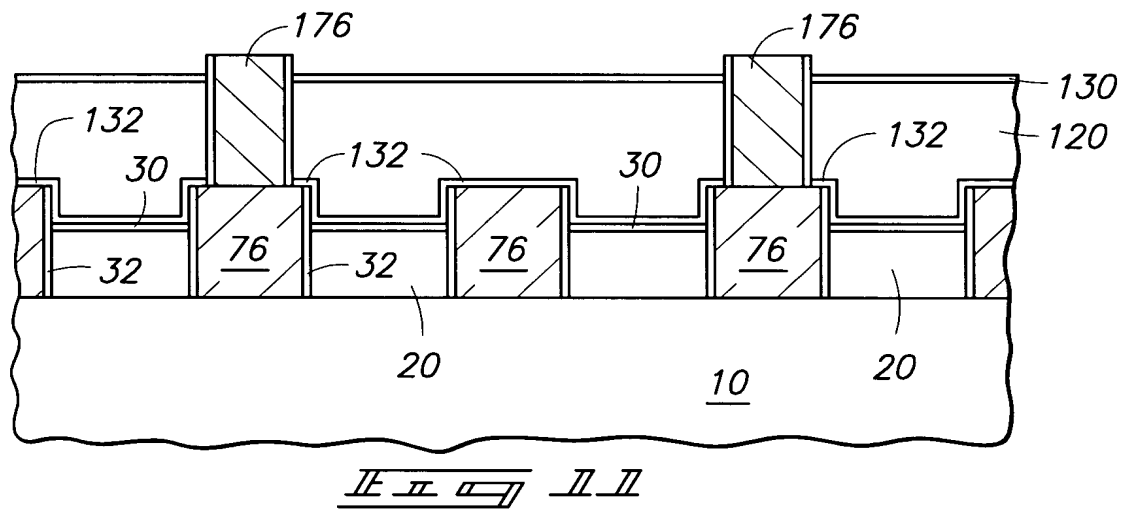
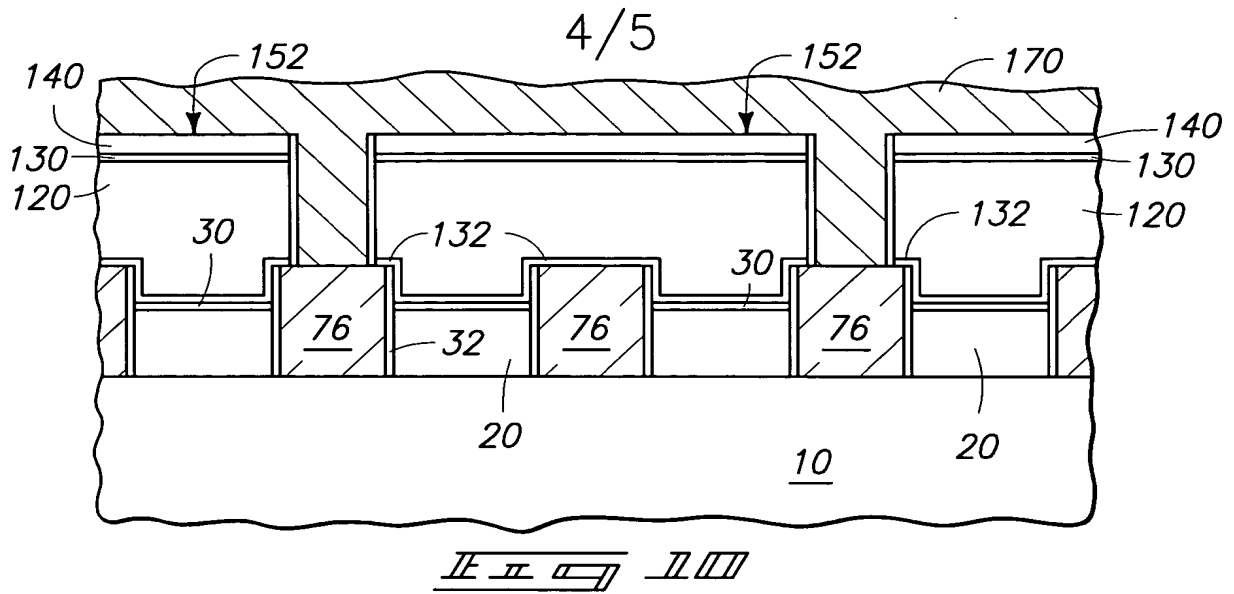
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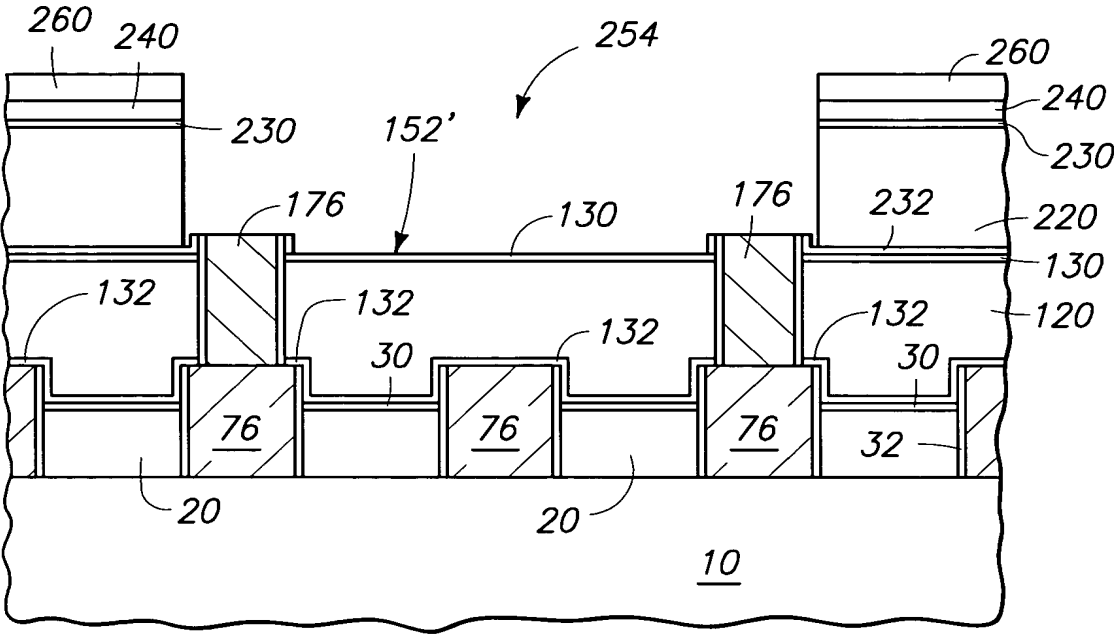
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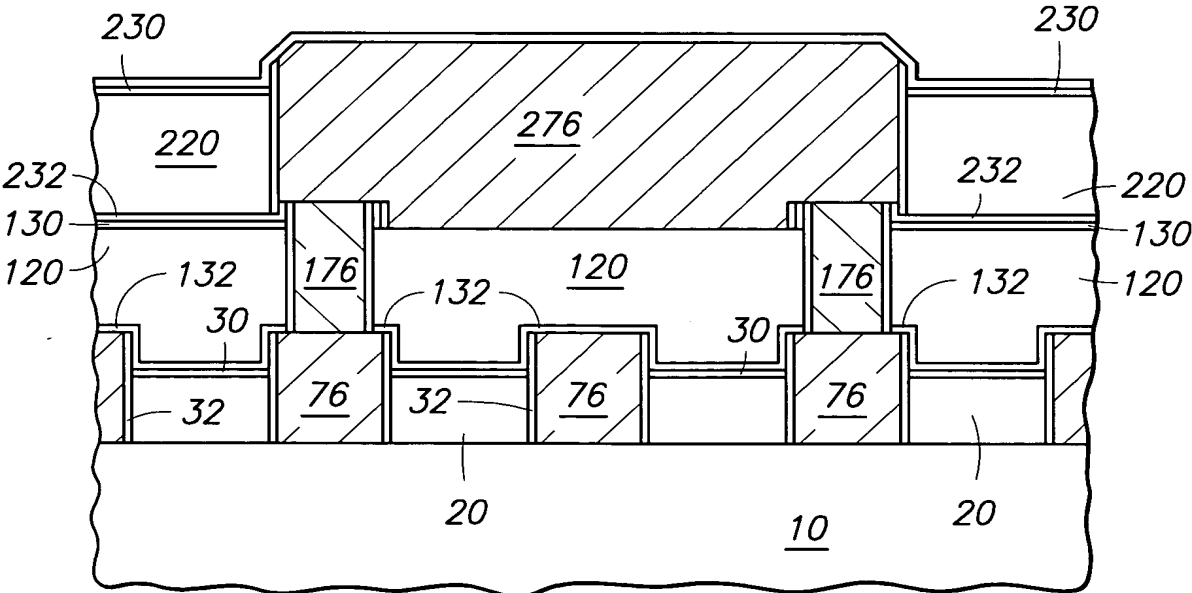
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